What is claimed is:

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waveguide,

| | 1. An optical module comprising: |
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| 2 | an under cladding having a flat shape as a |
| 3 | whole; |
| 4 | a first core which has a quadrangular cross |
| 5 | section and is placed on said under cladding; |
| 6 | a second core placed on a terminal end portion |
| 7 | of said first core; and |
| 8 | an over cladding placed in a region including |
| 9 | the terminal end portion of said first core and said |
| 10 | second core placed on the terminal end portion of said |
| 11 | first core, |
| 12 | wherein said under cladding and said first |
| 13 | core placed thereon constitute a first optical |
| 14 | waveguide, |
| 15 | said under cladding, the terminal end portion |
| 16 | of said first core placed on said under cladding, said |
| 17 | second core placed thereon, and said over cladding |
| 18 | placed on and around said second core constitute a mode |
| 19 | field size conversion portion, |
| 20 | said under cladding, said second core placed |
| 21 | on said under cladding, and said over cladding placed on |

said first core is made of silicon, and said first and second cores differ in

and around said second core constitute a second optical

- 26 cross-sectional shape.
 - 2. A module according to claim 1, wherein the
 - 2 terminal end portion is formed from a tapered portion
 - 3 whose cross-sectional area gradually decreases toward a
 - 4 distal end thereof.
 - 3. A module according to claim 1, wherein said
 - 2 over cladding is placed on and around said second core
 - 3 on said under cladding constituting the second optical
 - 4 waveguide and said second core on the terminal end
 - 5 portion constituting the mode field size conversion
 - 6 portion, and on said first core constituting the first
 - 7 optical waveguide.
 - 4. A module according to claim 1, wherein said
 - 2 under cladding is formed on a silicon substrate.
 - 5. A module according to claim 1, wherein said
 - 2 second core is made of a material higher in refractive
 - 3 index than said under cladding and lower in refractive
 - 4 index than silicon of said first core and the terminal
 - 5 end portion.
 - 6. A module according to claim 1, wherein said
 - 2 first core and at least a side portion of the terminal
 - 3 end portion are covered with a silicon oxide film.

- 7. A module according to claim 6, wherein said
- 2 second core on the terminal end portion is placed on the
- 3 silicon oxide film.
 - 8. A module according to claim 1, wherein said
- 2 second core covers a substantially entire region on an
- 3 upper surface of the terminal end portion.
 - 9. A module according to claim 1, wherein said
- 2 under cladding is formed from a silicon oxide film.
 - 10. A module according to claim 1, wherein said
- 2 under cladding is formed on a substrate.
 - 11. A module according to claim 1, wherein a
- 2 refractive index of said over cladding is higher than
- 3 that of said under cladding.
 - 12. A module according to claim 1, wherein a
- 2 specific refractive index difference between said second
- 3 core and said under cladding is larger than that between
- 4 said second core and said over cladding.
 - 13. A module according to claim 3, wherein said
- 2 over cladding placed on said core of the first optical
- 3 waveguide is continuous with said second core of the

- 4 second optical waveguide, and said over cladding and
- 5 said second core are made of the same material.
 - 14. A module according to claim 13, wherein a
- 2 second over cladding is placed on said over cladding
- 3 placed on said core of the first optical waveguide and
- 4 said second core of said second optical waveguide
- 5 continuous with said over cladding, and said second over
- 6 cladding is lower in refractive index than said second
- 7 core.
 - 15. A module according to claim 13, further
- 2 comprising regions where the material for said second
- 3 core does not exist at two positions symmetrical with
- 4 respect to a traveling direction of light in said second
- 5 core.
 - 16. A manufacturing method for an optical module,
- 2 comprising the steps of:
- forming an under cladding;
- 4 selectively forming, on said under cladding, a
- 5 first core which has a wire-like shape with a
- 6 quadrangular cross section and is made of silicon;
- 7 selectively forming a second core on a
- 8 terminal end portion of the first core and the under
- 9 cladding continuous with the terminal end portion; and
- 10 forming an over cladding on and around the

- 11 second core.
- wherein the under cladding and a portion of
- 13 the first core which is placed on the under cladding
- 14 constitute a first waveguide,
- the under cladding, the terminal end portion
- 16 of the first core placed thereon, and the second core
- 17 placed on the terminal end portion constitute a mode
- 18 field size conversion portion,
- 19 the under cladding and the second core placed
- 20 thereon constitute a second waveguide, and
- the first and second cores have different
- 22 cross-sectional shapes.
 - 17. A method according to claim 16, further
 - 2 comprising the step of oxidizing the first core and at
 - 3 least a side surface of the terminal end portion of the
- 4 first core after the step of forming the first core.
 - 18. A method according to claim 16, wherein the
- 2 terminal end portion is a tapered portion made of
- 3 silicon, whose cross-sectional area gradually decreases
- 4 toward a distal end of the first core.
 - 19. A method according to claim 17, wherein the
- 2 step of oxidizing the side surface of the terminal end
- 3 portion comprises the step of oxidizing the side surface
- 4 after masking the first core and an upper surface of the

- 5 terminal end portion of the first core with an
- 6 anti-oxidation film.
 - 20. A method according to claim 17, wherein the
- 2 step of oxidizing the first core and the side surface of
- 3 the terminal end portion of the first core comprises the
- 4 step of oxidizing to cover the first core and the
- 5 terminal end portion thereof in addition to the side
- 6 surface of the terminal end portion.
 - 21. A method according to claim 17, wherein the
- 2 step of oxidizing the first core and the side surface of
- 3 the terminal end portion of the first core comprises a
- 4 thermal oxidation process.
 - 22. A method according to claim 17, wherein the
- 2 step of oxidizing the terminal end portion comprises the
- 3 step of oxidizing the first core and a distal end of the
- 4 terminal end portion by a width dimension not less than
- 5 1/2 that before oxidation.
 - 23. A method according to claim 17, wherein
- in the step of forming the first core, a
- 3 silicon layer around the first core is left by a
- 4 predetermined thickness, and
- 5 the step of oxidizing the side surface of the
- 6 terminal end portion includes a process of converting

- 7 the silicon layer having the predetermined thickness and
- 8 left around the first core into a silicon oxide film.
 - 24. A method according to claim 23, wherein in the
- 2 step of forming the first core, the silicon layer left
- 3 around the first core has a thickness not less than 1/2
- 4 that of the first core after oxidation.
 - 25. A method according to claim 17, wherein the
- 2 step of oxidizing the side surface of the terminal end
- 3 portion of the first core includes the step of
- 4 increasing a refractive index of a silicon oxide film
- 5 formed within a range of refractive indices lower than a
- 6 refractive index of silicon.
 - 26. A method according to claim 17, wherein the
- 2 step of forming the second core comprises the step of
- 3 forming the second core extending to the first core
- 4 through the terminal end portion.
 - 27. A method according to claim 26, further
- 2 comprising the step of further forming a second over
- 3 cladding on the over cladding placed on the core of the
- 4 first optical waveguide and the second core of the
- 5 second optical waveguide continuous with the first
- 6 optical waveguide,
- 7 the second over cladding having a refractive

- 8 index than the second core.
 - 28. A method according to claim 26, further
- 2 comprising the step of forming regions where the
- 3 material for the second core does not exist at two
- 4 positions symmetrical with respect to a traveling
- 5 direction of light in the second core.